# **Electronic Supplementary Information**

## Large enhancement of ferroelectric polarization in Hf<sub>0.5</sub>Zr<sub>0.5</sub>O<sub>2</sub> films by low plasma energy pulsed laser deposition

Tingfeng Song,<sup>a</sup> Raul Solanas,<sup>a</sup> Mengdi Qian,<sup>a</sup> Ignasi Fina,<sup>\*a</sup> and Florencio Sánchez<sup>\*a</sup>

<sup>a</sup> Institut de Ciència de Materials de Barcelona (ICMAB-CSIC), Campus UAB, Bellaterra 08193, Barcelona, Spain

\* ifina@icmab.es, fsanchez@icmab.es



S1: Sketches of the PAr and PO2 partial pressures used to grow the films

**Figure S1**. In (a) the three series of films deposited at fixed  $P_{O2}$  are plotted using black squares ( $P_{O2} = 0.01$  mbar), red circles ( $P_{O2} = 0.05$  mbar), and blue up triangles ( $P_{O2} = 0.1$  mbar). In (b) the four series of films deposited at fixed  $P_{Ar}$  are plotted using black squares ( $P_{Ar} = 0$  mbar), red circles ( $P_{Ar} = 0.05$  mbar), blue up triangles ( $P_{Ar} = 0.1$  mbar), and green down triangles ( $P_{Ar} = 0.2$  mbar).

### S2: XRD $\theta$ -2 $\theta$ scans of the series of films



**Figure S2**: XRD  $\theta$ -2 $\theta$  scans of the series of films deposited under varied P<sub>Ar</sub> and fixed P<sub>02</sub> = 0.01 mbar (a), P<sub>02</sub> = 0.05 mbar (b), P<sub>02</sub> = 0.1 mbar (c), and the series of films deposited under varied P<sub>02</sub> and fixed P<sub>Ar</sub> = 0 mbar (d), P<sub>Ar</sub> = 0.05 mbar (e), P<sub>Ar</sub> = 0.1 mbar (f), P<sub>Ar</sub> = 0.2 mbar (g).

#### **S3: Simulation of Laue oscillations**

Figure S3 shows XRD  $\theta$ -2 $\theta$  scans of selected samples around the o-HZO(111) reflection. The scans were measured using a longer time that the scans show in Figure 1. The o-HZO(111) reflection is simulated (red curves) according to the equation.<sup>1</sup>

$$I(Q) = \left(\frac{\sin\left(\frac{QNc}{2}\right)}{\sin\left(\frac{Qc}{2}\right)}\right)^2$$

where  $Q = 4\pi \sin(\theta)/\lambda$  is the reciprocal space vector, N the number of unit cells along the out-of-plane direction and c the corresponding lattice parameter.



**Figure S3.** XRD  $\theta$ -2 $\theta$  scans around the o-HZO(111) reflection. (a) scans of films deposited under  $P_{O2} = 0.01$  mbar and the  $P_{Ar}$  pressure indicated in each panel. (b) scans of films deposited under  $P_{O2} = 0.05$  mbar and the  $P_{Ar}$  pressure indicated in each panel. (c) scans of films deposited under  $P_{O2} = 0.1$  mbar and the  $P_{Ar}$  pressure indicated in each panel. (c) scans of films in each panel are Laue fits. The thickness estimated by the fits is indicated in the corresponding panel.

#### S4: Thickness and growth rate as a function of PAr



**Figure S4**. Thickness (solid symbols, left axis) and growth rate (empty symbols, right axis) as a function of  $P_{Ar}$  for fixed  $P_{O2} = 0.01$  mbar (squares),  $P_{O2} = 0.05$  mbar (circles) and  $P_{O2} = 0.1$  mbar (triangles). Thickness of the films was estimated by simulation of Laue oscillations as described in Figure S3.

#### **S5: XRD pole figures**



**Figure S5**. XRD pole figures of the  $P_{O2} = 0.05$ ,  $P_{Ar} = 0.05$  mbar sample, from (a) o-HZO(-111) and (b) STO(111) reflections. (c) Corresponding  $\phi$ -scans around o-HZO(-111) and STO(111). The pole figures confirm that the orthorhombic phase is epitaxial, presenting four families of crystal variants.





**Figure S6**. Intensity of the o-(111) reflection, normalized to that of the STO(002) peak,  $I_{HZO(111)}/I_{STO(002)}$ , as a function of P<sub>O2</sub> and P<sub>Ar</sub>. In (a) P<sub>Ar</sub> is: 0 mbar (black squares), 0.05 mbar (red circles), 0.1 mbar (blue up triangles), and 0.2 mbar (green down triangles). In (b) P<sub>O2</sub> is: 0.01 mbar (black squares), 0.05 mbar (red circles), and 0.1 mbar (blue up triangles). The same dependences are obtained normalizing the intensity of the o-(111) reflection to that of the LSMO(002) peak, I<sub>HZO(111)</sub>/I<sub>LSMO(002)</sub>, as shown in Figure 2 of the manuscript.

#### S7: The normalized o-(111) reflection



**Figure S7**. The intensity of the o-(111) reflection, normalized to that of the LSMO(002) peak,  $I_{HZO(111)}/I_{LSMO(002)}$ , shown in Figure 2 of the manuscript as a function of P<sub>02</sub> and P<sub>Ar</sub> is normalized to the film thickness. In (a) P<sub>Ar</sub> is: 0 mbar (black squares), 0.05 mbar (red circles), 0.1 mbar (blue up triangles), and 0.2 mbar (green down triangles). In (b) P<sub>02</sub> is: 0.01 mbar (black squares), 0.05 mbar (red circles), and 0.1 mbar (blue up triangles).





**Figure S8**. Leakage - voltage curves of films deposited under varied  $P_{Ar}$  and fixed  $P_{O2} = 0.01$  mbar (a),  $P_{O2} = 0.05$  mbar (b),  $P_{O2} = 0.1$  mbar (c), and the series of films deposited under varied  $P_{O2}$  and fixed  $P_{Ar} = 0.05$  mbar (d),  $P_{Ar} = 0.1$  mbar (e),  $P_{Ar} = 0.2$  mbar (f).

#### References

 J. Lyu, I. Fina, R. Solanas, J. Fontcuberta and F. Sánchez, *Appl. Phys. Lett.*, 2018, 113, 082902.